

**UCF MATERIALS CHARACTERIZATION FACILITY
CORPORATE FEE SCHEDULE 2023-2024**

<u>Equipment</u>	<u>Hourly Rate</u>
Scanning Electron Microscopy (SEM)	
Jeol JSM-6480	150
Zeiss Ultra-55	200
Transmission Electron Microscopy (TEM)	
Jeol JEM-1-11	300
Tecnaï F30	450
Focused Ion Beam (FIB)	
FEI 200 TEM	250
Zeiss FIB Crossbeam	350
X-Ray Diffraction (XRD)	
XRD -- GN (Panalytical)	150
XRD -- TF (Panalytical)	200
XRD -- EC (Panalytical)	200
Secondary Ion Mass Spectrometry (SIMS)	
Cameca IMS-3F	300
PHI Adept	300
Miscellaneous	
XPS Escalab 250Xi	300
X-Ray Fluorescence Spectrometer (XRF) (Panalytical)	150
Sputter Coater (Quoram)	150
Other Instruments	
Metal Polisher Allied	50
Critical Point Dryer	50
Diamond Wafering	50
Dimple Grinder	50
PECS Gatan (Coating System)	75
Ion Milling	100
Ultra Microtom (Leica)	100
Leica Trimmer	75
Plasma Cleaner	50
Confocal Laser Scanning Microscope	100
Metallurgical Microscope	80
MicroRaman Spectroscopy	100
Profilometer	150
Reichert Optical Microscope	100